



566.41191X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Y. KURATA, et al.
Application No.: 10/049,672
Filed: February 15, 2002
For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL
POLISHING, AND METHOD OF POLISHING
Examiner: 1765
Group: D. Deo

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 8, 2004

Sir:

In response to the Office Action mailed January 8, 2004, please amend the
above-identified application as listed in the following, and as set forth on the following
pages:

Amendments to the Claims; and

Remarks are included following the amendments.